

RADICAL PLASMA SOURCE (REMOTE PLASMA SOURCE) - MA2000C-703BB

Categories: Plasma components



ADDITIONAL INFORMATION

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| Typ | Radical plasma source (Remote Plasma Source) |
| Process | Etching & Deposition |
| Output Connection Type | |
| Dielectric material | Ceramics |
| Mains voltage nominal [V] | 230 / 208 |
| Output Power [W] | 2000 |
| Frequency [MHz] | 2450 |